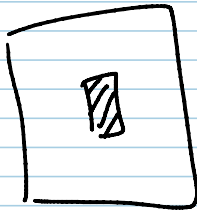


Nitride Thickness = 400nm

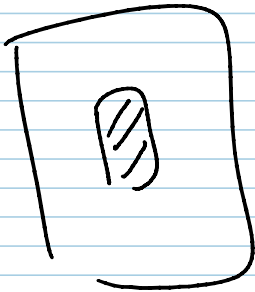
clear field / Dark field



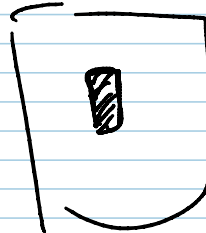
clear field



Dark field

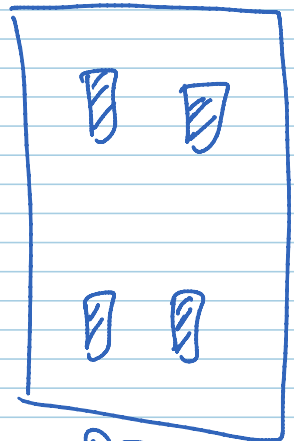


CF



DF

+ PR in the HW

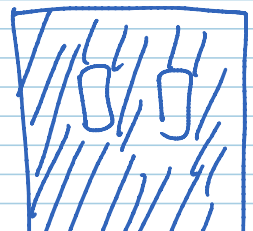


DF

2- PS 2µm

4- Nitride 400nm

5- etch PS / Nitride



5- etch PSG/Nitride

6- Poly. 500nm

7- etch Poly 1

8- PSG 100nm

10- etch PSG - Anchor

11- poly 2µm

12- PSG - hardmask 500nm

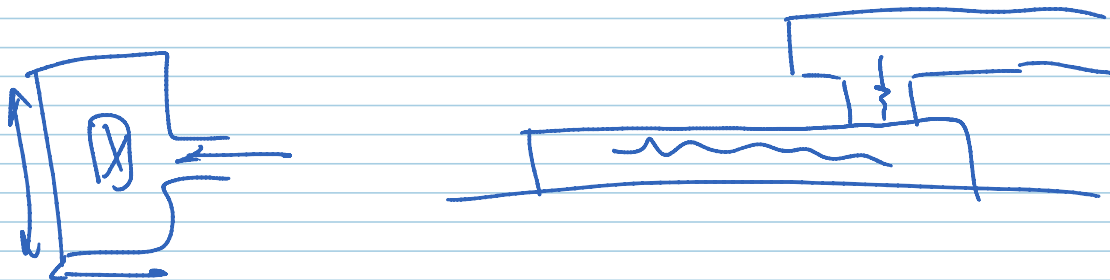
14- etch the hardmask/poly

15- etch all the oxide



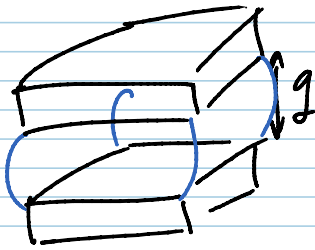
Oxide

PSG - oxide deposed with P

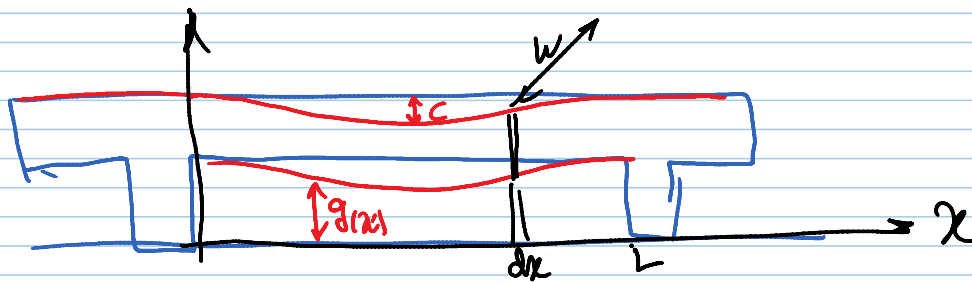
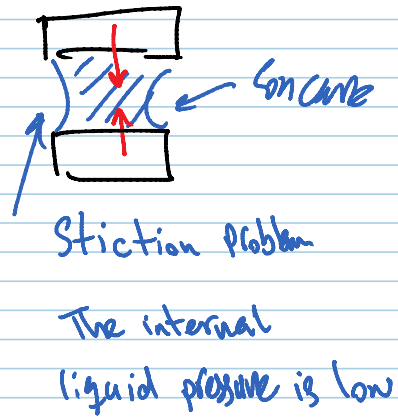
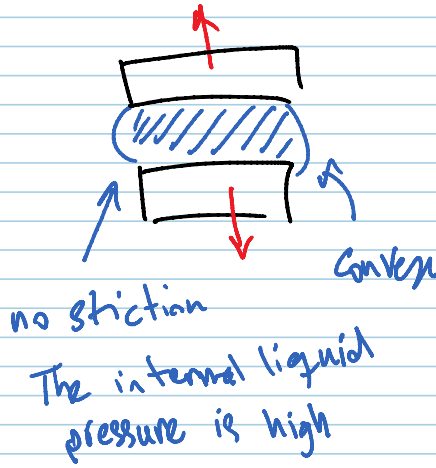


Stiction:



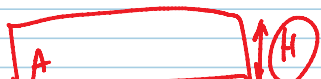
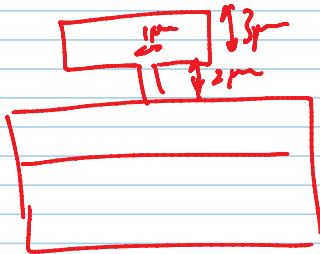


$$F = \alpha \frac{\gamma S_0}{g}$$

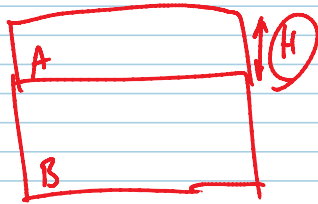


$$F = \int_0^L \frac{w dx}{g(x)}$$

$$F = kc$$

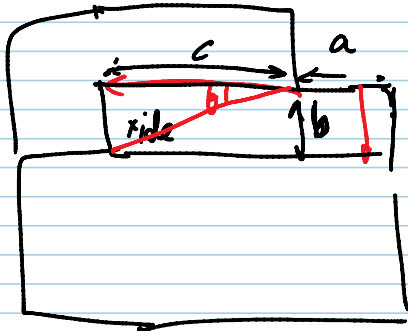


Sab
20%



20%

$$\frac{H \times a^2}{S_{ab}}$$



$$\frac{c}{ER} \quad \frac{b+c}{ER}$$

$$\frac{\sqrt{b^2+c^2}}{ER}$$

$$\cos \theta = \frac{c}{\sqrt{b^2+c^2}}$$

$$\sin \theta = \frac{b}{\sqrt{b^2+c^2}}$$

$$\frac{b}{ER_V} \quad \frac{c}{ER_H}$$

$ER_V \quad ER_H$

$$\frac{\sqrt{b^2+c^2}}{ER_H \frac{c}{\sqrt{b^2+c^2}} + ER_V \frac{b}{\sqrt{b^2+c^2}}}$$

$$= \frac{b^2+c^2}{c ER_H + b ER_V}$$

